

| 1.GENERAL INFORMATION | | i-line Stepper, Lens NA 0.57 MAX, Local |
|---|--|--|
| Tool ID | PAT53 | |
| Serial Number | 3127779 | |
| Vintage | 2003 | |
| OEM | Canon | |
| Model | FPA-5500iZ+ | |
| Process | LITHO - i-line STEPPER | |
| Software version | V70.09F.12 | |
| 2.WAFER SPECIFICATION | | |
| Wafer Size | 200MM | |
| Wafer Shape | SNNF (Semi Notch No Flat) | |
| Wafer Cassette | 8" PP Mirai | |
| SMIF Interface | No | |
| 3. SYSTEM CONFIGURATION | | |
| 3-1. Projection Lens / Illumination System | | |
| Magnification | 1/4 | |
| NA | 0.45 ~ 0.57 | |
| Field Size | 26 x 33mm | |
| Illumination σ (Conventional) | 0.75~0.40 (at NA=0.57) | |
| Illumination σ (Annular) | NA0.57 Outer σ 0.75 Inner σ 0.50 | |
| Light Source | i-line(365nm) | |
| Reticle Blind Setting Area | Max : Field size, Min : 0.4 x 0.4mm | |
| 3-2. Reticle Alignment | | |
| Alignment sensor | Image processing method | |
| 3-3. Reticle Stage | | |
| Reticle Holder size | 6inch | |
| Interferrometer | 3 axis | |
| 3-4. Wafer Alignment | | |
| Alignment sensor | Image processing method | |
| Alignment Light Source | 590±60nm (wavelength selectable) | |
| 3-5. Wafer Stage | | |
| Wafer Holder size | 200mm | |
| Interferrometer | 6 axis | |
| 3-6. Wafer Feeder | | |
| Pre-alignment | Edge detection system (non-contact) | |
| Chuck maintenance | Auto Chuck Clean & Load/Unload System | |
| Inline Type | Local | |
| 3-7. Reticle Changer | | |
| Library# | 29 | |
| Reticle Case Type | Canon Type | |
| Particle checker | Pellicle Particle Checker(PPC) | |



Canon Model **FPA-5500iZ+**

Air and Vacuum / 圧空系及びガス

| | Supply Pressure (Gauge) 供給圧 (圧空圧) (MPa) | Setting Pressure (Gauge) 設定圧 (圧空圧) (MPa) |
|------------------------------------|--|---|
| Pressured Air (P) 供給空気 (圧空) | 0.6 - 0.9 | 0.55/0.55/0.4/0.3 |
| Clean Dry Air (CDA) 清浄乾燥空気 (圧空) | 0.35 - 0.9 | 0.3 |
| No gas (Nz) 無ガス (圧空) | 0.4 - 0.9 | 0.35 |
| Vacuum (V) 真空 (圧空) | -0.1 ~ -0.07 | -0.07 |

Cooling Water / 冷却水

| Supply Temperature 供給温度 (℃) | Supply Pressure 供給圧 (MPa) | Difference 差圧 | Flow 流量 (l/min) |
|--------------------------------|------------------------------|------------------|--------------------|
| 25 - 35 | 0.2 - 0.4 | 0.10 ~ | 26.0 - 63.0 |

Power Supply / 電源

| | Voltage 電圧 | Frequency 周波数 | Phase 相数 | Wire 線径 | Power Consumption 消費電力 |
|--------|---------------|------------------|-------------|------------|---------------------------|
| MAIN 1 | 200V | 50/60Hz | 3φ | 3W,1PE | 9.7kVA |
| MAIN 2 | 200V | 50/60Hz | 3φ | 3W,1PE | 22.0kVA |

DRAWING No. / 電気部品図番 - 部品番号: CC1-0120B001

Weight / 重量

Stagger main unit + Environmental chamber
スタagger-本体 + 環境チェンバー: 11610Kg

Serial Number / 製造番号

Stagger main unit
スタagger-本体: No.3127779

Environmental chamber
環境チェンバー: CD1603XR072

Production Years / 製造年月

2003-12

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